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| OPE | IN THE UNITED STATES PA |
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| JAN Applicati | t: Peter V. Loeppert and Sung Bok Lee |
| For: | Raised Microstructure of Silicon |

IN THE UNITED STATES PATENT AND TRADEMAR

TC 3700 MAIL ROOM

CERTIFICATE OF MAILING

I hereby certify that this Information Disclosure Statement is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Box DD,

Commissioner for Patents, Washington, D.C. 20231

on December 12, 2001

Serial No.: 09/910,110

Filed: July 20, 2001

Examiner: Not Yet Assigned

Based Device

Attorney Docket No. 1864 P 071

Art Unit: 3729

TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT BEFORE MAILING DATE OF EITHER A FINAL ACTION OR NOTICE OF ALLOWANCE (37 C.F.R. § 1.97(c))

BOX DD Commissioner for Patents Washington, D.C. 20231

Dear Sir:

Applicant submits herewith Form PTO-1449, "Information Disclosure Statement," and a copy of the references listed thereon.

Since this Statement is being filed before the mailing date of the first Official Action on the merits, no certification or fee is necessary. The Commissioner is hereby authorized to charge payment of any deficit in these fees to Deposit Account No. 23-0280. A duplicate copy of this sheet is enclosed for that purpose.

Respectfully submitted,

Thomas K. Stine, Reg. No. 32,310 WALLENSTEIN & WAGNER, LTD.

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